



Integrated Device Technology, Inc.
2975 Stender Way, Santa Clara, CA - 95054

PRODUCT/PROCESS CHANGE NOTICE (PCN)

PCN #: L0007-04 DATE: 7/31/2000
Product Affected: 74LVC16244, 74LVC16245
74LVCH162244
Manufacturing Location Affected: IDT Salinas Fab
Date Effective: 10/31/2000

MEANS OF DISTINGUISHING CHANGED DEVICES:

- ☐ Product Mark
☐ Back Mark
☒ Date Code Prefix from "X" to "XG"
☐ Other

Contact: Bimla Paul
Title: Product Assurance Manager
Phone #: 408-654-6419
Fax #: 408-492-8362
E-mail: bima.paul@idt.com

Attachment: ☒ Yes ☐ No

Samples:

DESCRIPTION AND PURPOSE OF CHANGE:

- ☐ Die Technology
☐ Wafer Fabrication Process This change has been implemented to add TSMC (Taiwan) as an alternate fab to IDT fab (Salinas).
☐ Assembly Process
☐ Equipment
☐ Material
☐ Testing
☒ Manufacturing Site
☐ Data Sheet
☐ Other

RELIABILITY/QUALIFICATION SUMMARY:

Available upon request.

CUSTOMER ACKNOWLEDGMENT OF RECEIPT:

IDT records indicate that you require written notification of this change. Please use the acknowledgement below or E-Mail to grant approval or request additional information. If IDT does not receive acknowledgement within 30 days of this notice it will be assumed that this change is acceptable.

IDT reserves the right to ship either version manufactured after the process change effective date until the inventory on the earlier version has been depleted.

Customer: _____

☐ **Approval for shipments prior to effective date.**

Name/Date: _____

E-Mail Address: _____

Title: _____

Phone# /Fax# : _____

CUSTOMER COMMENTS:

IDT ACKNOWLEDGMENT OF RECEIPT:

RECD. BY: _____

DATE: _____



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PCN Summary

PCN Type: Fab Site Change

Commodity Logic

Forecast or Execute Execute

Planned or Unplanned Planned

Data Sheet Change No Change

Detail of Change

This process change has been implemented to add TSMC Fab 9, 0.5 μ m process for 74LVC16244, 74LVC16245, 74LVCH162244.

Process / Design Changes

	<u>Current Die Rev - X</u>	<u>New Die Rev - XG</u>
Wafer Fab Technology	CEMOS 8.0	0.5 μ m
Poly Gate	0.5 μ m	0.5 μ m
Minimum Gate Oxide	140Å	115Å
Wafer Size	6"	8"
Fab Facility	Fab 2 (Salinas)	TSMC Fab 9

Conversion schedule (Estimated)

	Sample Availability	Production Shipments
74LVC16244	September, 2000	October 31, 2000
74LVC16245	Available	October 31, 2000
74LVCH162244	September, 2000	October 31, 2000



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Qualification Plan QLG-00-07

Test Vehicle: 74LVC16245 Expected Completion Date: October 31, 2000

Test	Lot SS/ Acc #	Lot # 1	Lot # 2	Lot # 3
Bond Pull EIA/JESD22-B116	5/0			
Die Shear Mil-Std-883, Method 2019	3/0			
Ball Shear EIA/JESD22-B116	5/0			
Operating Life Test (Dynamic) Mil-Std-883, Method 1005	77/0			
85/85(THB) or HAST EIA/JESD22-A110	45/0			
Pressure Pot EIA/JESD22-A102	45/0			
Thermal Shock Mil-Std-883, Method 1011	45/0			
Temperature Cycling Mil-Std-883, Method 1010	45/0			
ESD: HBM Mil-Std-883, Method 3015	3/0			
ESD: CDM	3/0			
Latch-Up Immunity EIA/JESD78	10/0			
Electrical Characterization Per Applicable Datasheet	10/0			